

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:
Yuxiang Wang, et al.
Serial No.: 10/799,146
Confirmation No.: 7933
Filed: March 12, 2004
For: Method of Depositing an
Amorphous Carbon Film for
Etch Hardmask Application

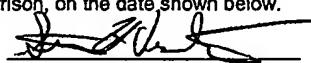
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§ Group Art Unit: 2813
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§ Examiner: Monica D. Harrison
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September 13, 2006
Date


Steven H. VerSteeg

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Dear Sir:

RESPONSE TO FINAL OFFICE ACTION DATED JULY 13, 2006

In response to the Final Office Action dated July 13, 2006, having a shortened statutory period for response set to expire on October 13, 2006, please enter this response and reconsider the claims pending in the application for the reasons discussed below. Although Applicants believe that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/008244/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper. **Remarks** begin on page 5 of this paper.